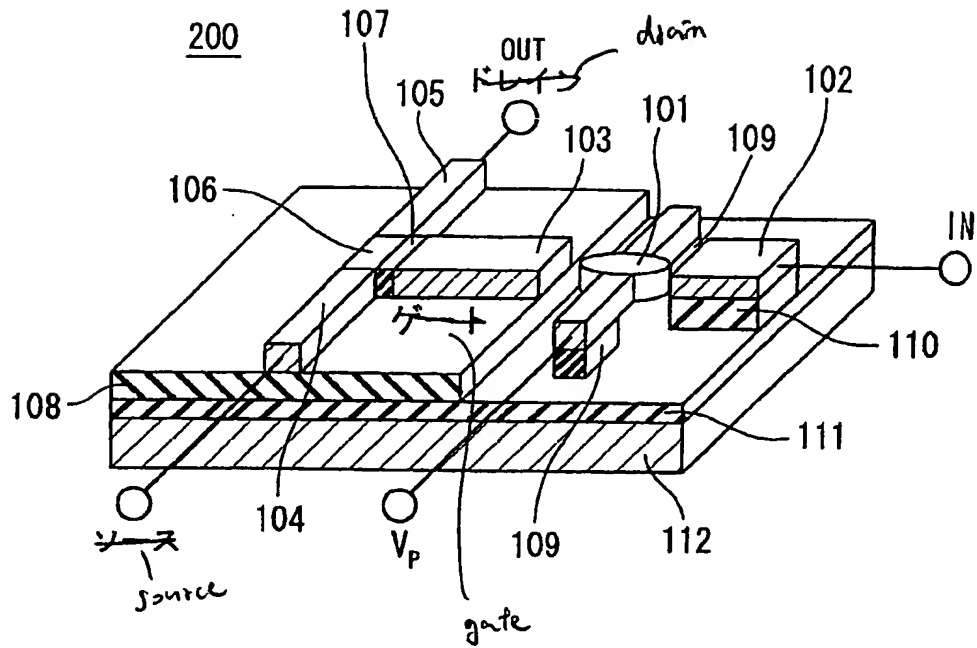
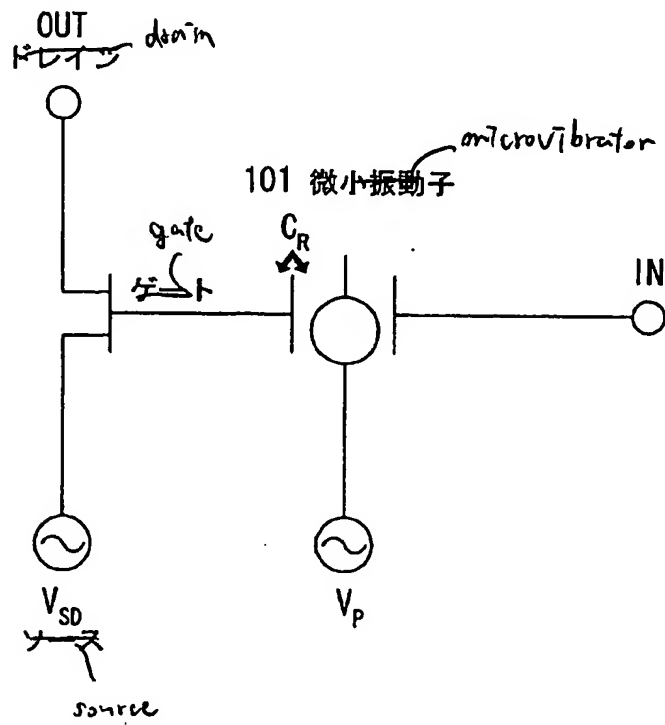


~~[図2]~~ Fig. 2

(a)



(b)



~~[図3]~~ Fig.3

(a)

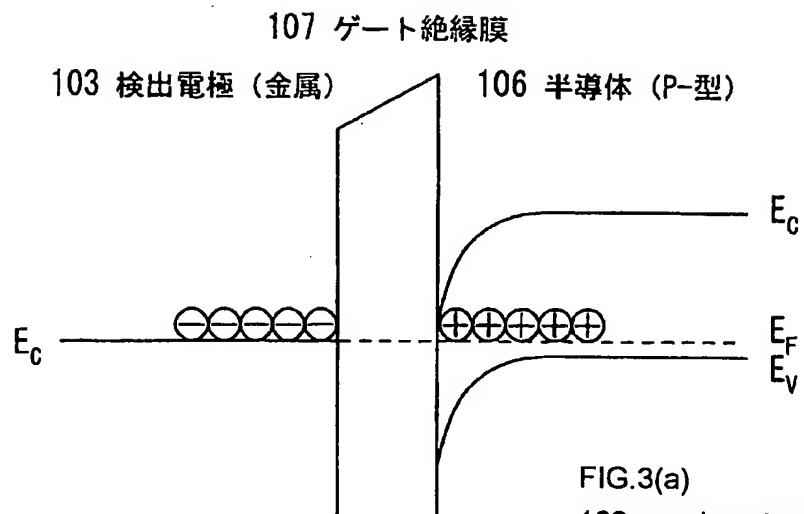


FIG.3(a)

103 sensing electrode (metal)

106 semiconductor (P-type)

107 gate insulating film

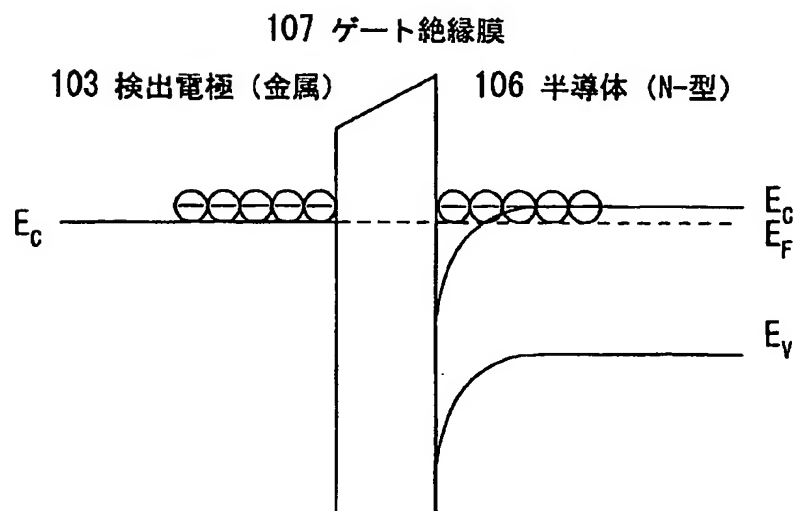
FIG.3(b)

(a)

103 sensing electrode (metal)

106 semiconductor (N-type)

107 gate insulating film



[4]

Fig. 4

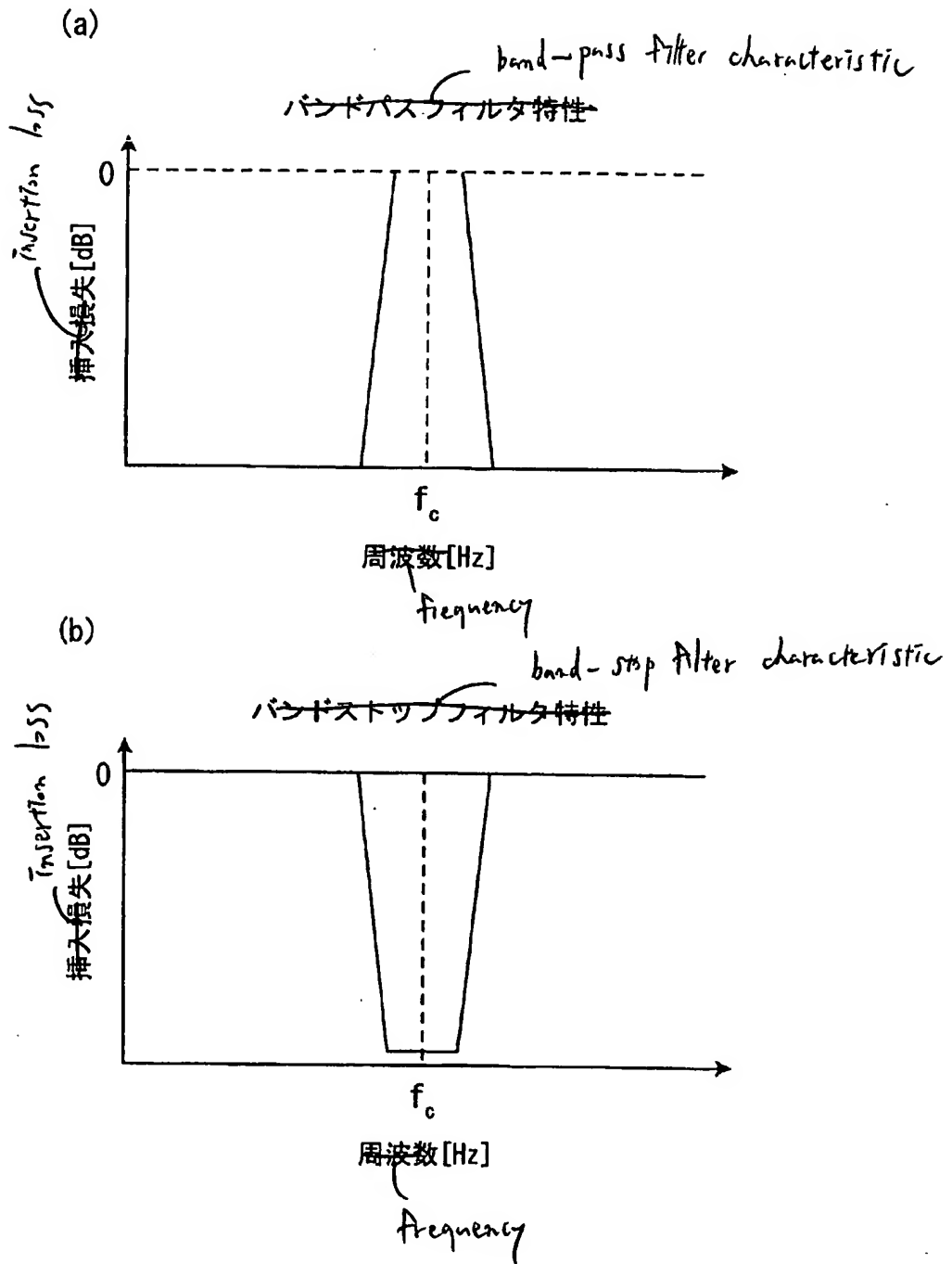
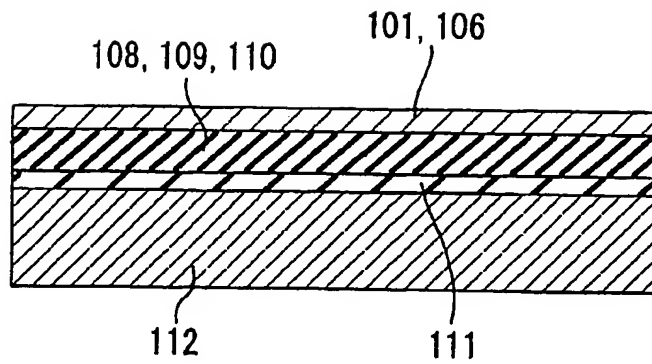
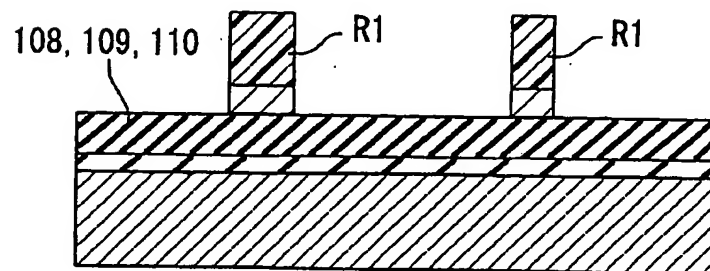



Fig. 5

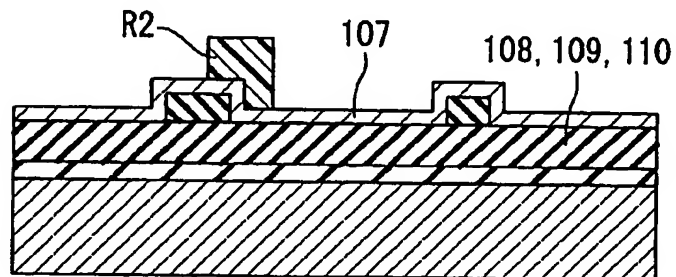
(a)



(b)



(c)



(d)

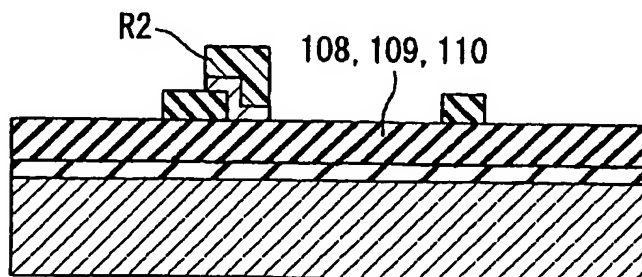
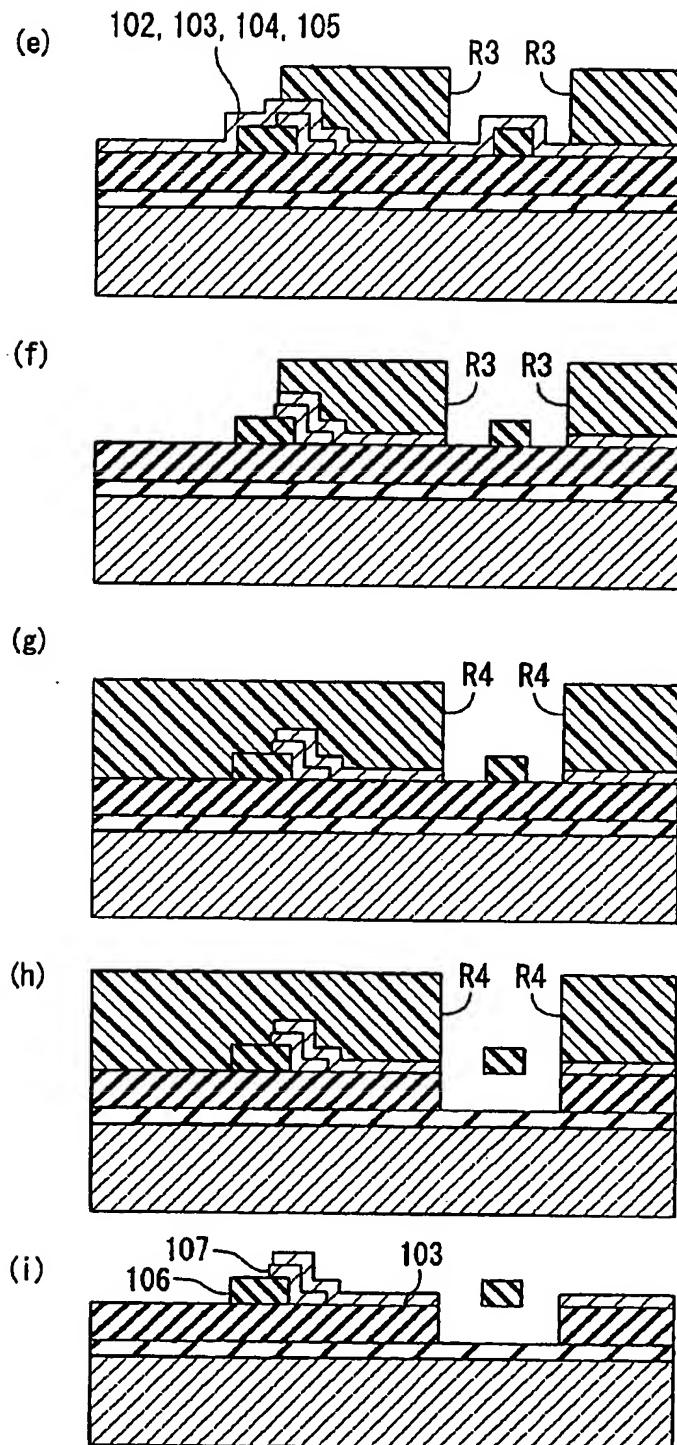
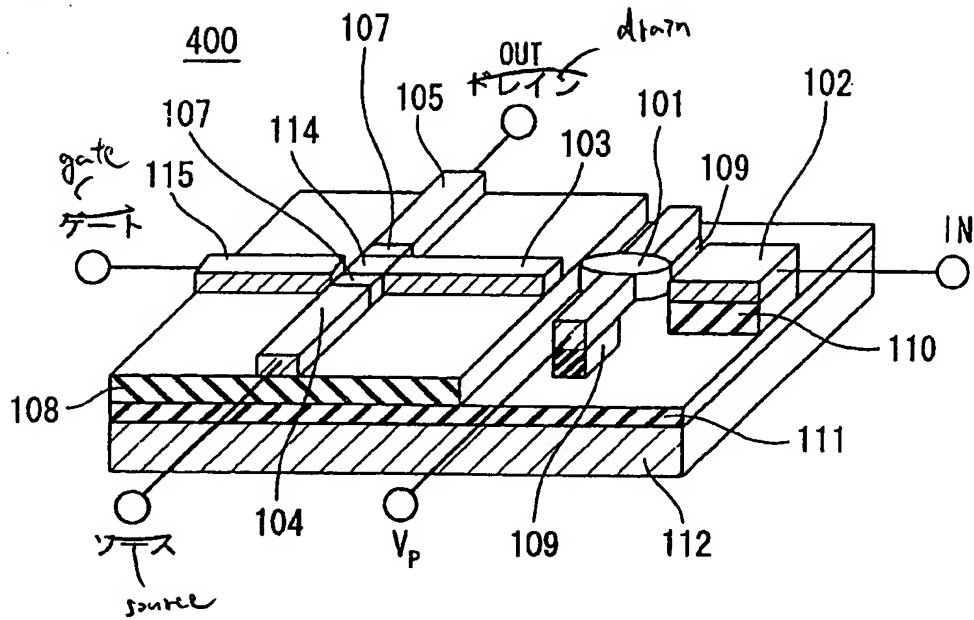


Fig. 6

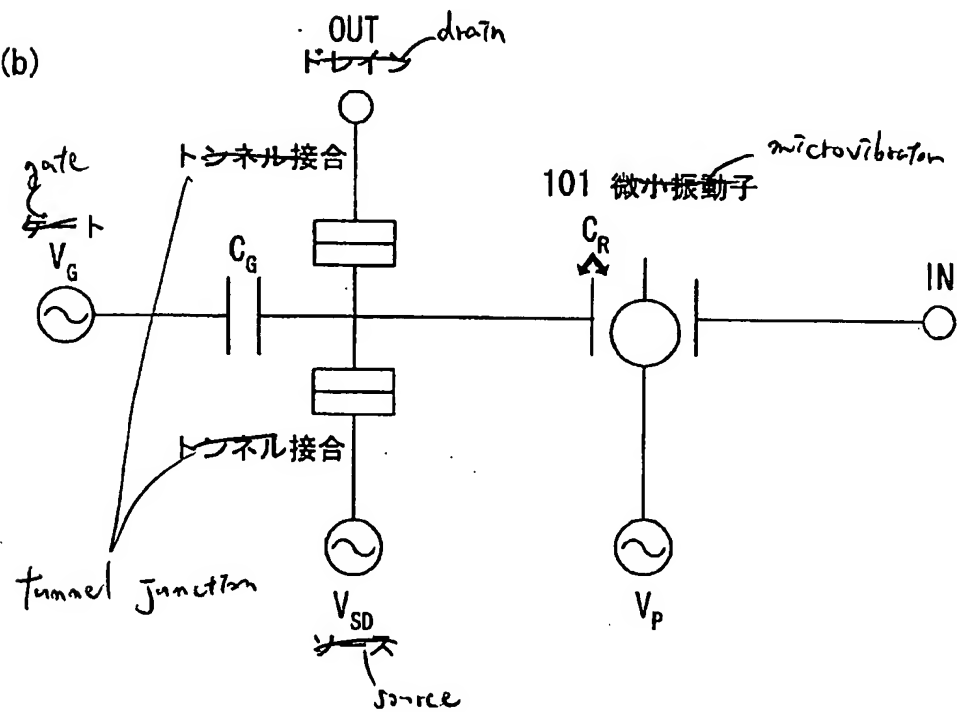


~~[図8]~~ Fig. 8

(a)



(b)



~~図9~~ Fig. 9

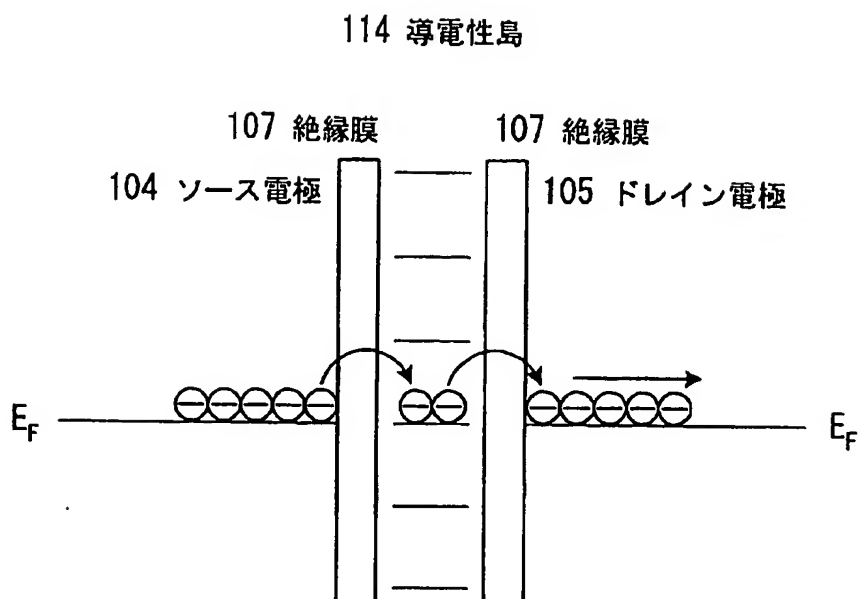


FIG.9:

104 source electrode

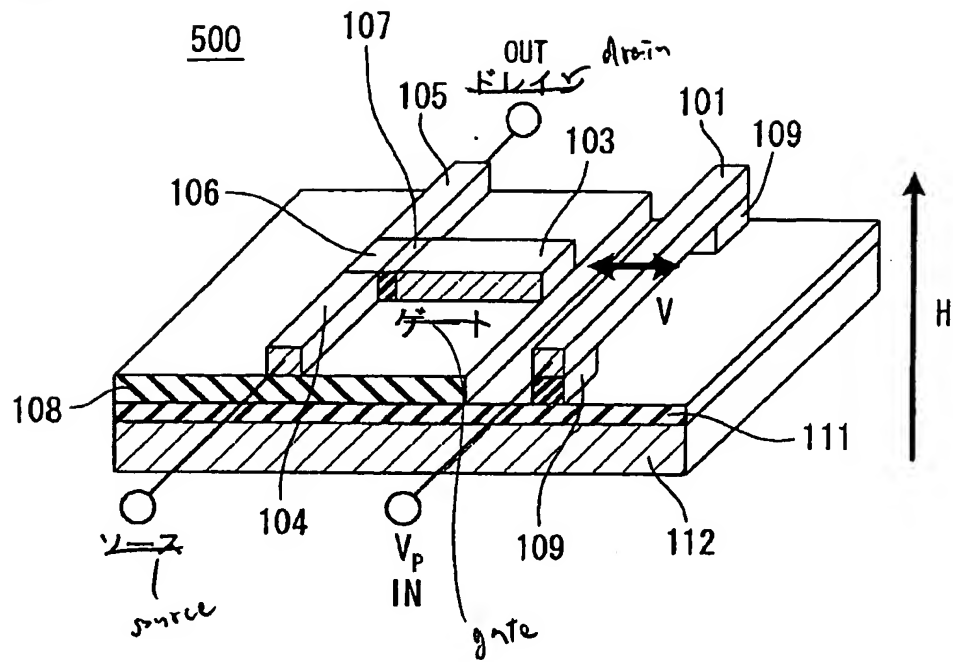
105 drain electrode

107 insulating film

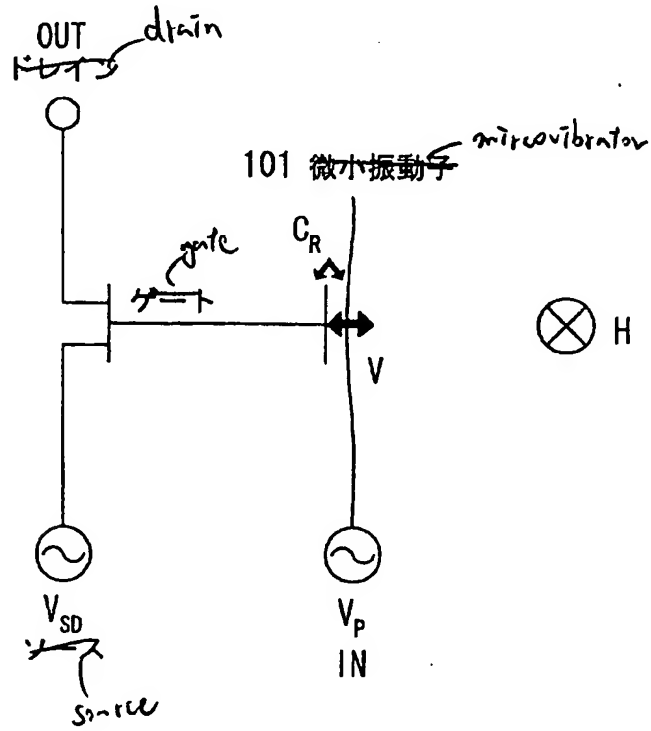
114 conductive island

[5110] **Fig. 10**

(a)

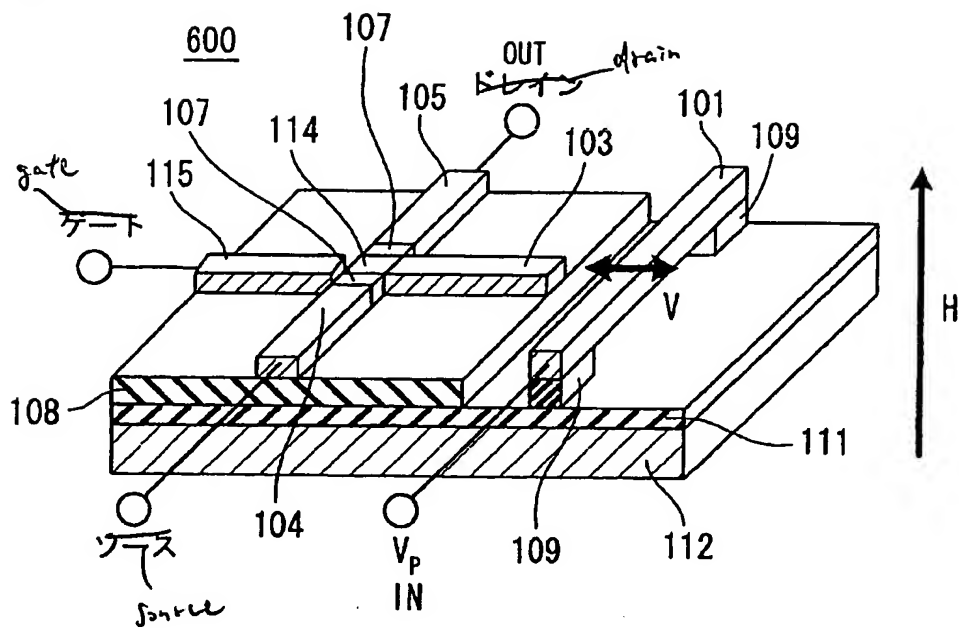


(b)

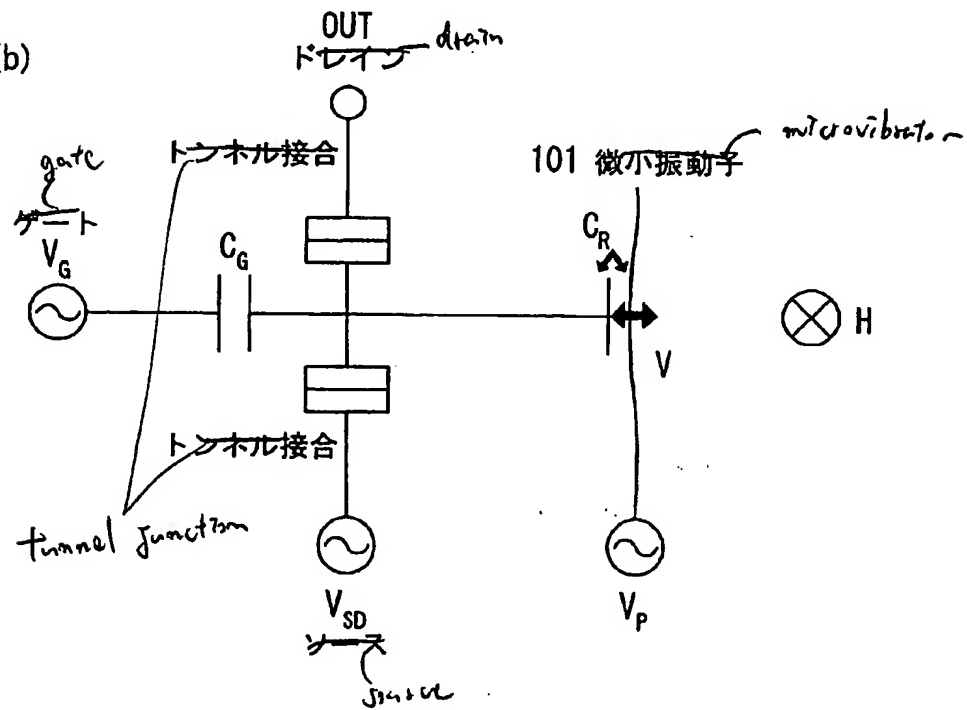


~~[Fig. 11]~~ Fig. 11

(a)



(b)



~~図12~~ Fig. 12

